

UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Daniel Alvarez, Jr. and Jeffery J. Spiegelman

Application No.:

10/692,018

Group:

1724

Filed:

October 23, 2003

Examiner: Frank M. Lawrence, Jr.

Confirmation No.:

8519

For:

METHOD FOR PURIFICATION OF LENS GASES

USED IN PHOTOLITHOGRAPHY

CERTIFICATE OF MAILING OR TRANSMISSION

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AMENDMENT

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

This Amendment is being filed in response to the Office Action mailed from the U.S.

Patent and Trademark Office on August 26, 2005, in the above-identified application.

Reconsideration and further examination are requested.

A one-month extension of time to respond to the Office Action is respectfully requested.

A Petition for a One-Month Extension of Time and the appropriate fee are being filed concurrently with this Amendment.

Please amend the application as follows:

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